**DOCKET NO.:** DXPZ-0005 / 03-0494D **PATENT** 

**Application No.:** 10/560,537 **Office Action Dated:** June 3, 2011

This listing of claims will replace all prior versions, and listings, of claims in the application.

## **Listing of Claims:**

1. (*Currently amended*) A vortex reactor, comprising:

a substantially frustum-shaped portion forming a reaction chamber therein, said frustum-shaped portion having a narrower part that is downwardly oriented;

an axial flow apparatus fluidly connected to the reaction chamber for creating an axial gas flow in said reaction chamber, whereby the axial flow apparatus <u>comprises a flow restrictor</u> <u>optionally comprising a vertical rod attached thereto and is configured so as to provide an axial gas flow into the bottom of the reaction chamber, directed upward;</u>

a circumferential flow apparatus fluidly connected to the reaction chamber for creating a circumferential gas flow in said reaction chamber;

a plasma generating device, configured so that the flow restrictor and/or the vertical rod optionally attached thereto can act as a first electrode and a wall of the frustum-shaped reaction chamber can act as a second electrode of the plasma generating device;

an apparatus for applying a voltage difference between said first electrode and said second electrode;

a solid particulate inlet connected to said reaction chamber.

- 2. (*Currently amended*) The vortex reactor of claim 1, wherein said axial flow apparatus comprises a gas supply inlet and an apparatus selected from the group consisting of a porous bed and a flow restrictor.
- 3. (*Currently amended*) The vortex reactor of claim [[2]] 1, wherein said flow restrictor further comprises at least one channel therein which provides a fluid connection between said gas supply and said reaction chamber.
- 4. (Original) The vortex reactor of claim 3, wherein said circumferential flow apparatus is located below said flow restrictor.

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5. (Original) The vortex reactor of claim 4, wherein a cross-sectional area of said at least one channel tapers from a first, cross-sectional area at an end of the channel that is fluidly connected to said gas supply, to a smaller, second, cross-sectional area at an end of the channel that is fluidly connected to the reaction chamber.

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- 6. (Original) The vortex reactor of claim 1, wherein said apparatus for creating circumferential gas flow comprises a gas supply and one or more gas inlet nozzles oriented tangentially relative to a sidewall of the narrower part of said frustum-shaped portion.
- 7. (Original) The vortex reactor of claim 1, wherein said reactor further comprises a bottom entry tube fluidly connected to said reaction chamber at the narrower part of said frustum-shaped portion, and said apparatus for creating circumferential gas flow comprises a gas supply and one or more gas inlet nozzles oriented tangentially relative to a sidewall of the bottom entry tube.

## 8-9. (*Canceled*)

- 10. (*Currently amended*) The vortex reactor of claim  $\underline{1}$  [[9]], wherein said flow restrictor is positioned to provide a small gap between said first and second electrodes for initiation of a plasma generating electrical arc at said small gap, and said flow restrictor is shaped to provide a gradual increase in the size of said gap between said first and second electrodes in an upward direction to provide a geometry for producing a gliding arc in said reaction chamber.
- 11. (Canceled)
- 12-36. (Canceled)